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| APPLICATION NO.   | FILING DATE | FIRST NAMED INVENTOR | ATTORNEY DOCKET NO. | CONFIRMATION NO. |
|---|-------------|----------------------|---------------------|------------------|
| 10/629,806  | 07/30/2003  | Miwa Kozawa          | 030923              | 9494             |
| 38834 7590 05/01/2007<br>WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP<br>1250 CONNECTICUT AVENUE, NW |             |                      | EXAMINER            |                  |
|   |             |                      | LEE, SIN J          |                  |
| SUITE 700<br>WASHINGTON, DC 20036   |             | ART UNIT             | PAPER NUMBER        |                  |
|   |             |                      | 1752                |                  |
|   |             |                      |                     |                  |
|   |             |                      | MAIL DATE           | DELIVERY MODE    |
|   |             |                      | 05/01/2007          | PAPER            |

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

|  | Application No.  | Applicant(s)  |  |  |  |  |
|--|--|---|--|--|--|--|
|  | 10/629,806   | KOZAWA ET AL.   |  |  |  |  |
| Office Action Summary  | Examiner   | Art Unit  |  |  |  |  |
|  | Sin J. Lee   | 1752  |  |  |  |  |
| The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply   |  |   |  |  |  |  |
| A SHORTENED STATUTORY PERIOD FOR REPLY WHICHEVER IS LONGER, FROM THE MAILING DA  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If NO period for reply is specified above, the maximum statutory period w  - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b). | ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tim vill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONEI | I.  lely filed  the mailing date of this communication.  D (35 U.S.C. § 133). |  |  |  |  |
| Status   |  |   |  |  |  |  |
| Responsive to communication(s) filed on <u>02 Fe</u> This action is <b>FINAL</b> . 2b)⊠ This     Since this application is in condition for allowar closed in accordance with the practice under E   | action is non-final.<br>nce except for formal matters, pro   |   |  |  |  |  |
| Disposition of Claims  | ,  |   |  |  |  |  |
| 4) ☐ Claim(s) 1-4,8,9 and 12-21 is/are pending in the 4a) Of the above claim(s) is/are withdraw 5) ☐ Claim(s) 13 is/are allowed. 6) ☐ Claim(s) 1-4,8,9,12 and 14-21 is/are rejected. 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or   | vn from consideration.   |   |  |  |  |  |
| Application Papers   |  |   |  |  |  |  |
| 9)☐ The specification is objected to by the Examine 10)☒ The drawing(s) filed on 30 July 2003 is/are: a)☐ Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11)☐ The oath or declaration is objected to by the Ex   | ☑ accepted or b)☐ objected to be drawing(s) be held in abeyance. See ion is required if the drawing(s) is obj  | e 37 CFR 1.85(a).<br>lected to. See 37 CFR 1.121(d).                          |  |  |  |  |
| Priority under 35 U.S.C. § 119   |  |   |  |  |  |  |
| 12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:  1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the prior application from the International Bureau * See the attached detailed Office action for a list  | s have been received. s have been received in Applicati rity documents have been receive u (PCT Rule 17.2(a)).   | on No ed in this National Stage   |  |  |  |  |
| Attachment(s)  |  |   |  |  |  |  |
| <ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>Information Disclosure Statement(s) (PTO/SB/08)</li> <li>Paper No(s)/Mail Date <u>2/2/2007</u>.</li> </ol>  | 4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:   | ate   |  |  |  |  |

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#### **DETAILED ACTION**

1. In view of the amendment of February 2, 2007, previous 102(e) rejection over Ishibashi et al'657 is hereby withdrawn.

## Claim Rejections - 35 USC § 102

- 2. The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.
- 3. Claims 1-4, 8, 9, 12 and 14-21 are rejected under 35 U.S.C. 102(e) as being anticipated by Kanda et al (US 6,555,607 B1).

In Example 1, Kanda teaches a water-soluble resin composition (which is used in producing semiconductor devices) which contains polyvinyl alcohol (as a water soluble resin), methoxy methylated melamine (present crosslinking agent as well as present nitrogen-containing compound), 2,4,7,9-tetramethyl-5-decyne-4,7-diol polyethoxylate (present primary alcohol ethoxylate compound, present alkoxylate surfactant, and present alcohol surfactant), water and isopropyl alcohol (present alcohol solvent). Kanda applies his water-soluble resin composition onto a resist pattern (which is formed onto a silicon wafer) to prepare a water-soluble resin coating and then the contact hole resist pattern is formed (see Example 2). Therefore, Kanda teaches present inventions of claims 1-4, 8, 9 and 14-21.

With respect to present claim 12, Kanda teaches that combination of two or more water soluble resins can be used in his composition and as one of example for suitable water soluble resin, Kanda includes styrene-maleic anhydride copolymer (see col.2, lines 35-53). Based on this teaching, one skilled in the art would readily envisage using

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styrene-maleic acid copolymer in addition to the polyvinyl alcohol in Kanda's Example 1 as his water soluble resins. Therefore, the prior art teaches present invention of claim 12.

## Claim Rejections - 35 USC § 103

- 4. The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.
- 5. Claims 1-4, 8, 9, 12 and 14-21 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ishibashi et al (US 6,579,657 B1) in view of Mizutani et al (US 2002/0015909 A1) or Yasunami et al (US 2002/0028409 A1).

In col.2, lines 38-57, Ishibashi teaches a method for manufacturing a semiconductor device: A first resist pattern is formed from a first resist (a mixture of novolac resin and a naphthoquinonediazide photosensitive agent) on a semiconductor base layer. A second resist is formed on the first resist pattern which generates crosslinking reaction in the presence of an acid. A crosslinked film is formed at a portion of the second resist contacting with the first resist pattern by the agency of an acid fed from the first resist pattern. Non-crosslinked portions of the second resist are removed (i.e., developed) to form a second resist pattern. Finally, the semiconductor base layer is subjected to etching through the second resist pattern used as a mask.

Specifically, in his Example 11, Ishibashi teaches a second resist (which is used as a resist pattern thickening material) which contains *polyvinyl acetal* (a water-soluble resin), (N-methoxymethyl)methoxyethylene*urea* (a crosslinking agent), (N-methoxymethylurea (a crosslinking agent), *N-methoxymethylurea* (a

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crosslinking agent) and pure water. N-methoxymethylurea (NH<sub>2</sub>-C(=O)-N(H)-CH<sub>2</sub>OCH<sub>3</sub>) also teaches present nitrogen-containing compound. Ishibashi teaches (col.9, line 6-12) that in order to improve the film-forming properties, surface active agents such as nonionic polyoxyethylene nonylphenyl ether type surfactant can be added to the second resist material. Polyoxyethylene nonylphenyl ether and presently recited compounds such as polyoxyethylene alkyl ether (which is also a polyoxyalkylene alkylether compound), polyoxyethylene-polyoxypropylene condensation product, sorbitan fatty acid ester compound (which is also a fatty acid ester surfactant) are well known in the art as equivalent non-ionic surfactants as evidenced by Mizutani, [0126] or Yasunami, [0226]. Because such teachings of equivalency were known in the art at the time the invention was made, it would have been obvious to one skilled in the art to use polyoxyethylene alkyl ether, polyoxyethylene-polyoxypropylene condensation product or sorbitan fatty acid ester compound as Ishibashi's non-ionic surfactant with a reasonable expectation of improving film-forming properties of his second resist material. Thus, Ishibashi in view of Mizutani or Yasunami would render present inventions of claims 1-4, 8, 9 and 16-21.

With respect to present claim 12, Ishibashi teaches that his water-soluble resin (which examples include polyvinylacetal as well as styrene-maleic acid copolymer) for the second resist can be used singly or in combination of two or more. Based on this teaching, one skilled in the art would readily envisage using styrene-maleic acid copolymer in addition to the polyvinyl acetal in Ishibashi's Example 11 as his water

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soluble resins. Therefore, Ishibashi in view of Mizutani or Yasunami would render obvious present invention of claim 12.

With respect to present claims 14 and 15, Ishibashi teaches (col.9, lines 14-22) that the solvents for the second resist may be water and alcoholic solvents such as isopropyl alcohol. Therefore, Ishibashi in view of Mizutani or Yasunami would render obvious present inventions of claims 14 and 15.

#### Allowable Subject Matter

- 6. Claim 13 is allowed. None of the cited prior arts teaches or suggests present second resin of claim 13.
- 7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sin J. Lee whose telephone number is 571-272-1333. The examiner can normally be reached on Monday-Friday from 9:00 am EST to 5:30 pm EST.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Cynthia Kelly, can be reached on 571-272-1526. The fax phone number for the organization where this application or proceeding is assigned is **571-273-8300**.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should

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you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

2. J. L.

S. Lee

April 28, 2007